

## piezo electrical nosepiece focusing device for microscopes

# **MIPOS N100/2**

- 100µm adjustment range(open loop)
- moves the nosepiece with nanometres accuracy
- high resonant frequency
- additional load up to 5kg
- optionally integrated sensor system

## application:

- surface scanning and analysis
- semi-conductor analysis equipment
- scanning interferometry
- biotechnology (e.g. cell inspection)
- ray focusing for print processes



fig.: MIPOS N 100/2

#### Concept

The series MIPOS N100/2 design for moving the whole nosepiece objective revolver on microscopes with nanometres accuracy. The MIPOS N100/2 offers a positioning and scanrange up to 100  $\mu$ m. These systems can be used with objectives, and objective revolvers with an aperture up to 20 mm.

The mechanical flexure design with an integrated preload, offers a high resonant frequency and a high parallel motion. A load of 5kg can be carried without any impact in the optical axis.

The MIPOS N100/2 is designed for universal use. Only an adapter plate for the specific mechanical interface is necessary. Please contact us for additional information.

The MIPOS 100N/2 is a cost effective and simple solution to get a fine tuning focusing device for the microscope nosepiece with several micro objectives.

### **Specials**

Adapter plates for the mounting of the MIPOS N100/2, to your existing assembly are easily installed.

This allows for the use of the MIPOS N100/2 with any objectives, thus, making this process no longer time consuming and costly.

Because of its stable construction the system has a high resonant frequency of 140Hz (with a mass of 5kg) making it suitable for dynamical applications especially in the field of confocal microscopy.

The high stiffness of the system reduces overshooting behavior during scan applications.

For long term positioning stability the MIPOS N100/2 can be equipped with a high resolution feedback sensor.

## Mounting/Installation

The MIPOS N100/2 is integrated between the objective revolver and tripod.

The MIPOS N100/2 should not be work under compression loaded >30N.

Please note that the MIPOS 100/2 reduces the mechanical distance between the microscopy stage and the objective lens. The optical axis is extended by 37mm.

All necessary connecting cables leave the MIPOS on the right to the back.

Please see on page 2 the typical mounting area for the MIPOS N100/2.





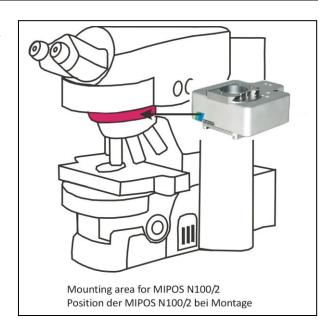
## technical data:

series MIPOS N100/2		unit	MIPOS N100/2	MIPOS N100/2 CAP
part no.		-	O-395-00	O-395-06
axis		-	Z	
motion open loop (±10%)*		μm	100	
motion closed loop (±0,2%)*		μm	-	80
capacitance (±20%)**		μF	21.3	
integrated measurement system		-	-	capacitive
resolution open loop***		nm	0.2	
closed loop***		nm	-	1
resonant frequency		Hz	480	
additional load = 5000g		Hz	140	
stiffness		N/µm	3	
max. load		N	50	
lateral force limit		N	30	
rotational error (full motion) [roll/pitch/gier]		μrad	< 20	
voltage range		V	-20 +130	
connector	voltage	-	LEMO 0S.302 + ODU, 3pol. serie L	
	sensor	-	-	LEMO 0S.650
cable length		m	1.0	1.6
min. bend radius of cable		mm	>15	
material		-	stainless steel	
dimensions (I x w x h)		mm	111/100/48	
central aperture		mm	32	
weight		g	1100	
max. lens weight		g	5000	
option for standard microscopes		-	yes	
option for inverse microscopes		-	upon request	

- \* typical value measured with ENV 800 amplifier
- \*\* typical value for small electrical field strength
- \*\*\*The resolution is only limited by the noise of the power amplifier and metrology.

The series of micro lens and objective positioning systems MIPOS offers a travel range from 20µm up to 500µm in z-axis. Available for standard and inverted microscopes.

More details under "z-axis-lenspositioning" www.piezojena.com.



Additional microscopy stages for XY axes available under "series-PXY-AP" www.piezojena.com

Rights reserved to change specifications as progress occurs without notice!



